

FORMATION OF PERIODIC MICRO- AND NANOSTRUCTURES ON THE SURFACE OF MONOCRYSTALLINE SILICON USING LASER

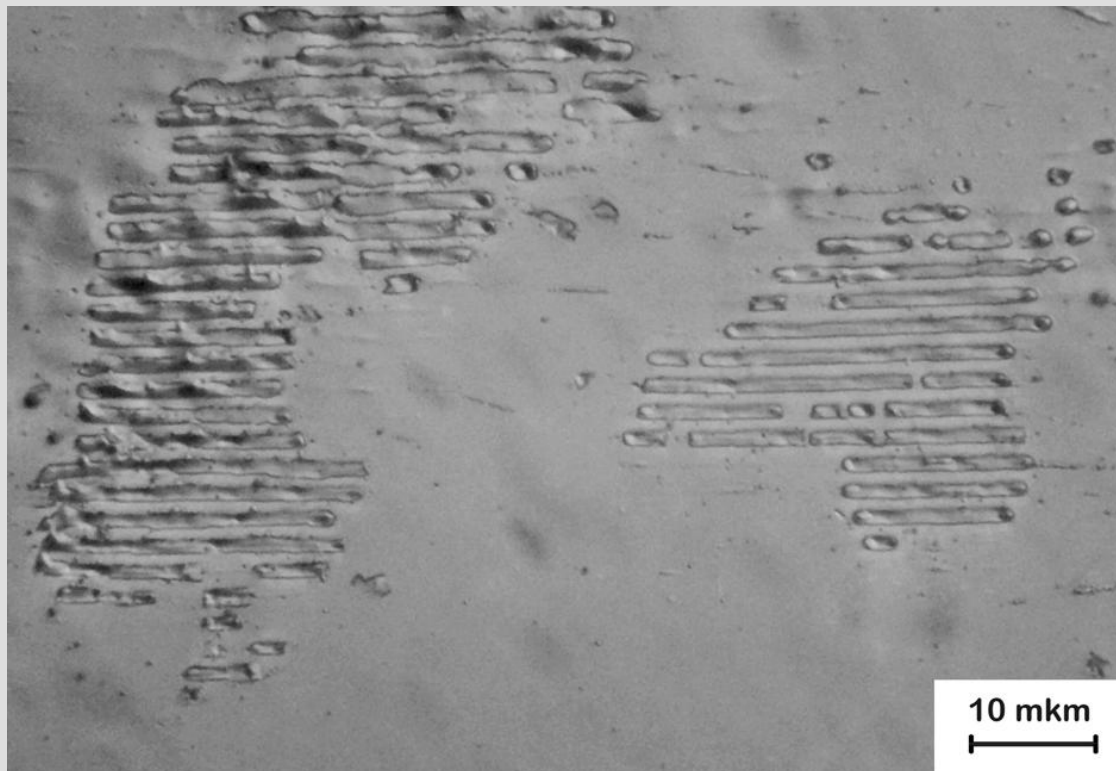
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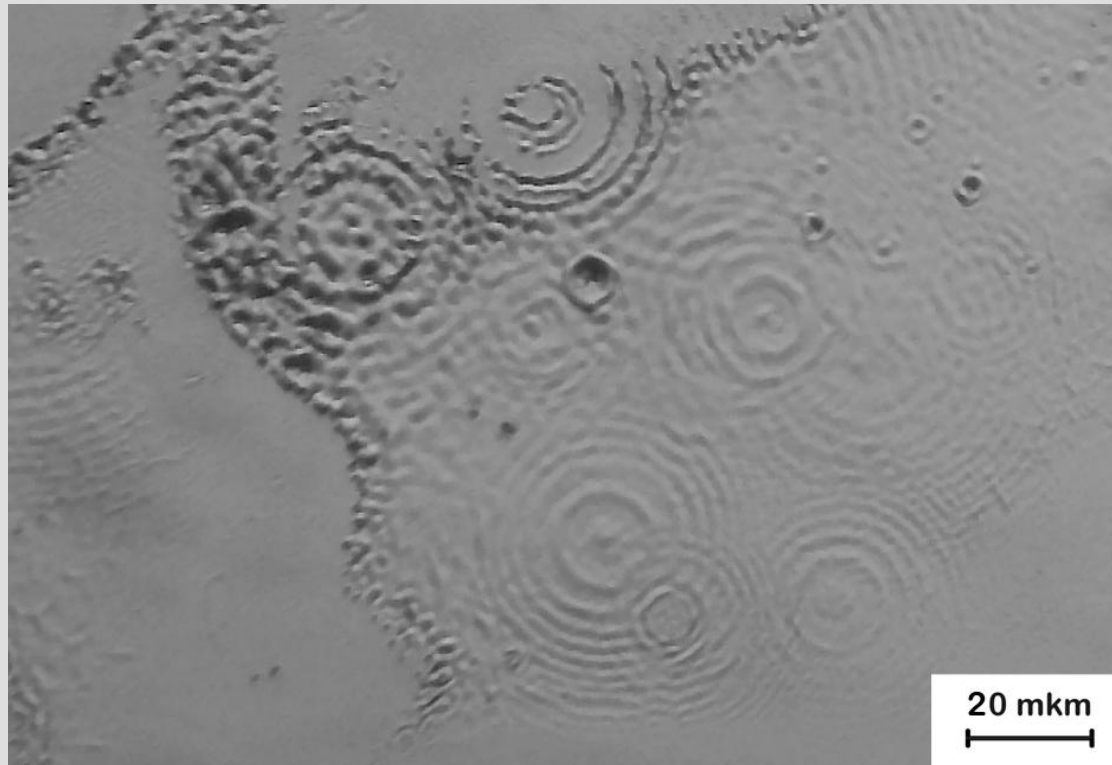
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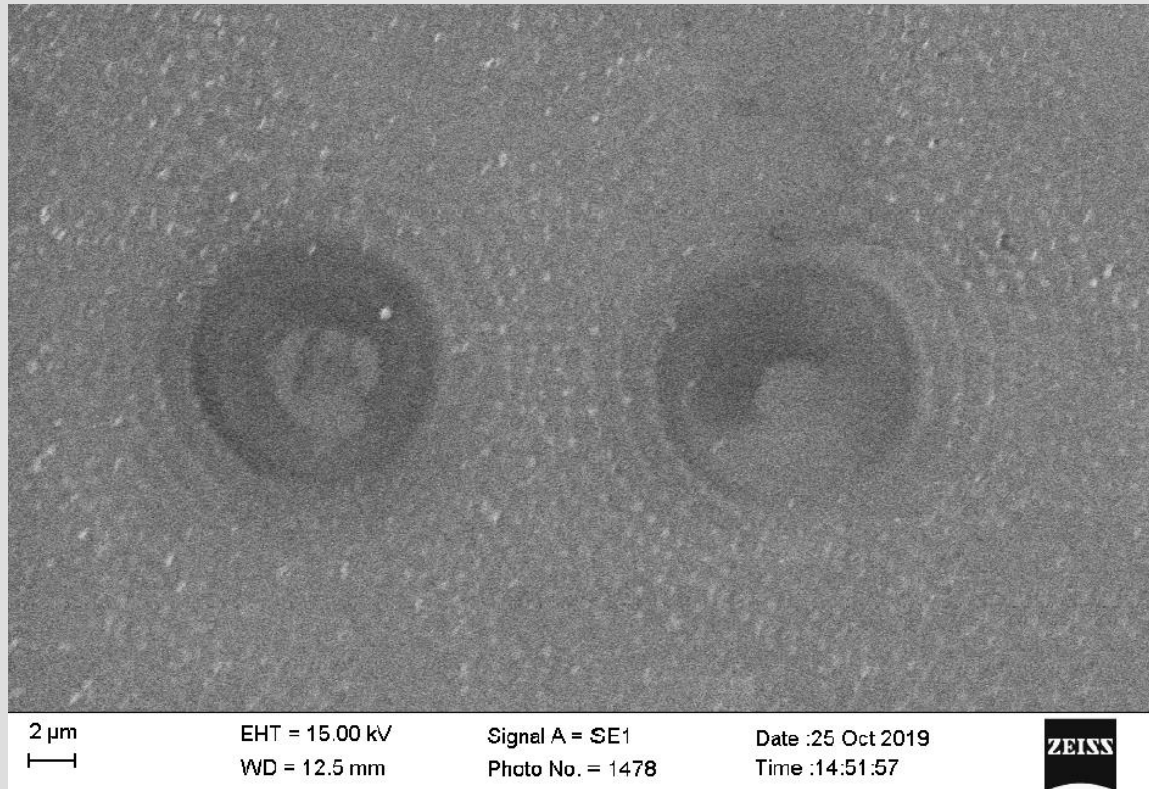
Micrograph of Si surface in the laser pulse zone
Nd:YAG laser ($\lambda = 1.06 \mu\text{m}$, $\tau_i = 10 - 15 \text{ ns}$)



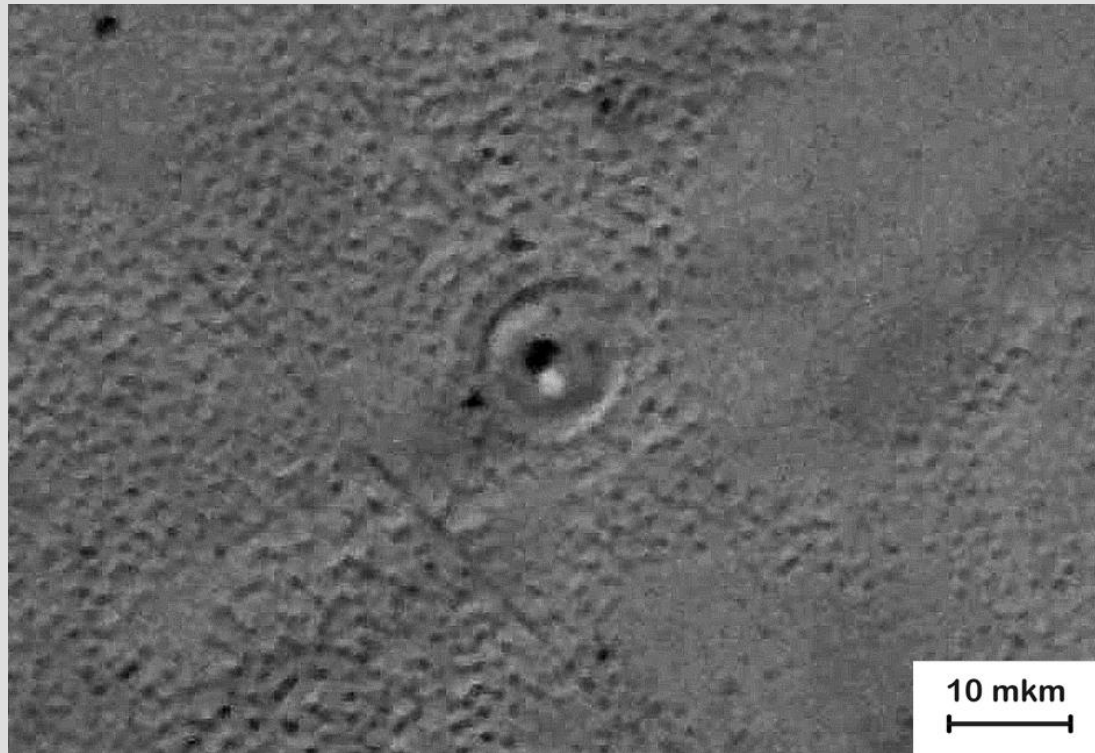
Micrograph of Si surface in the laser pulse zone
Nd:YAG laser ($\lambda = 1.06 \mu\text{m}$, $\tau_i = 10 - 15 \text{ ns}$)



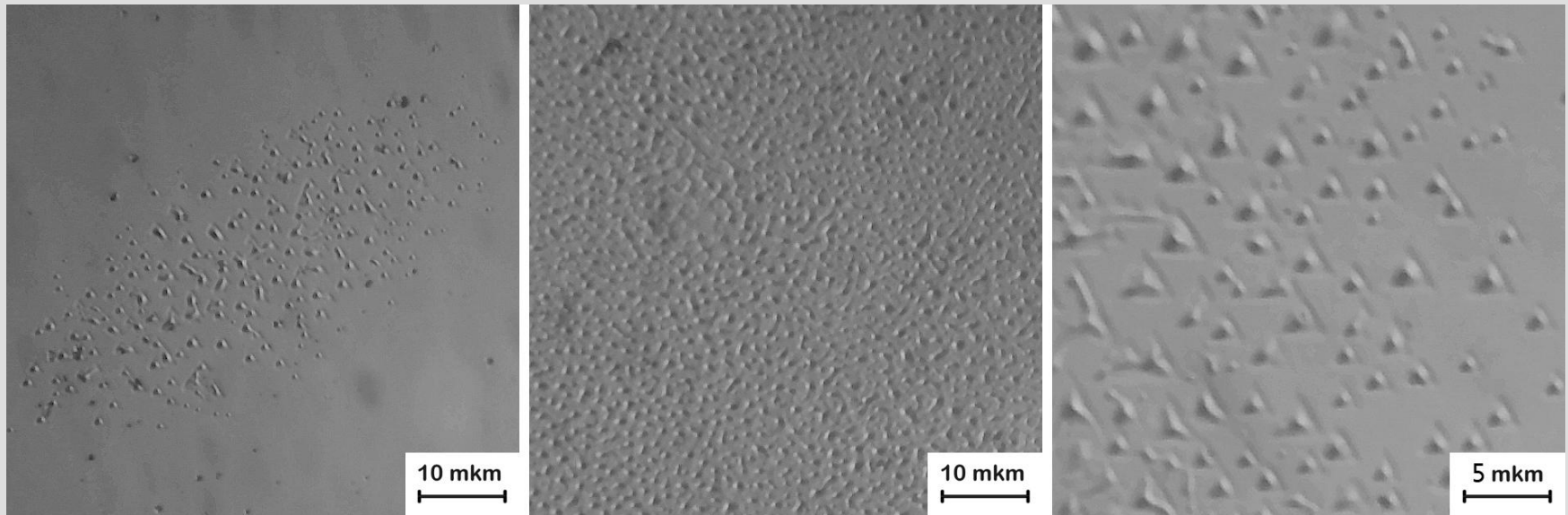
Micrograph of Si surface in the laser pulse zone
ruby laser ($\lambda = 0.69 \mu\text{m}$, $\tau_i = 5 \text{ ms}$)



Micrograph of Si surface in the laser pulse zone
ruby laser ($\lambda = 0.69 \mu\text{m}$, $\tau_i = 5 \text{ ms}$)



Micrograph of Si surface in the laser pulse zone
Nd:YAG laser ($\lambda = 1.06 \mu\text{m}$, $\tau_i = 1 \text{ ms}$),
crystallographic orientation (111)



Micrograph of Si surface in the laser pulse zone
 CO_2 laser ($\lambda = 10.6 \mu\text{m}$, $\tau_i = 0.3 \text{ s}$),
crystallographic orientation (100)

